

What is claimed is:

1. A semiconductor factory automation (FA) system, comprising:  
at least one processor for driving a program process and  
providing processor state information, wherein the processor state  
information includes an availability of a central processing unit,  
an availability of a disk and a state of the program process related  
to said processor;  
a storing means for storing the processor state information in  
a real time;  
a monitoring means for retrieving the processor state  
information in said storing means to monitor said processor; and  
a displaying means for displaying the processor state  
information retrieved.
2. The semiconductor FA system as recited in claim 1, wherein  
said displaying means includes:  
a first display space for displaying the availability of the  
central processing unit related to said processor; and  
a second display space for displaying the availability of the  
disk related to said processor.
3. The semiconductor FA system as recited in claim 2, wherein  
said displaying means further includes:  
a first light emitting device for emitting a light when the disk  
has failed;  
a second light emitting device for emitting the light when the

program process is in a down state; and

a third light emitting device for emitting the light when a communication between said monitoring means and said processor is disconnected.

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4. The semiconductor FA system as recited in claim 3, wherein said displaying means further includes:

a third display space for displaying identification information of the program process of the down state.

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5. The semiconductor FA system as recited in claim 4, wherein said processor is coupled to Ethernet™ supplied by Xerox Corporation.

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6. The semiconductor FA system as recited in claim 5, wherein said at least one processor includes a first processor and a second processor.

7. The semiconductor FA system as recited in claim 6, further comprising:

20 a semiconductor processing means coupled to said first processor for processing a semiconductor wafer cassette containing a predetermined number of semiconductor wafers;

a stocking means coupled to said second processor for stocking the semiconductor wafer cassette; and

25 a transportation means for transporting the semiconductor wafer cassette from said semiconductor processing means to said stocking means or from said stocking means to said semiconductor processing

means.

8. A method for monitoring at least one server in a semiconductor factory automation (FA) system, comprising the steps of:

5       a) providing server state information from at least one server to a real-time database, wherein the server state information includes an availability of a central processing unit, an availability of a disk and a state of a program process related to the server;

10      b) storing the server state information in the real-time database;

      c) retrieving the server state information to monitor the server; and

15      d) displaying the server state information retrieved.

15      9. The method as recited in claim 8, wherein said step d) includes the steps of:

      d1) displaying the availability of the central processing unit related to the server; and

20      d2) displaying the availability of the disk related to the server.

10. The method as recited in claim 9, wherein said step d) further includes the steps of:

25      d3) emitting a light when the disk has failed; and

      d4) emitting the light when the program process is in a down state.

11. The method as recited in claim 10, wherein said step d)  
further includes the step of:

d5) displaying identification information of the program  
5 process of the down state.

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*A1*